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Overview of the Micro Vertex Detector for the PANDA experiment D. Calvo (INFN-Torino) on behalf of the PANDA MVD group

- Spatial resolution (tens of μm in $\rho \phi$, <100 μm inz)
 - Time resolution (< 10 ns)
 - Continuous readout at ~ 10⁷ interactions /s (clock signal @160 MHz)
 - Limited material budget $X/X_0 \le 1 \%$ / layer
 - Radiation tolerance < 10¹⁴ n _{1 MeV eq} cm⁻²
 - \geq 4 hits per track
 - Room temperature operation
 - Routing and services backwards only











Two inner cylindrical layers around the interaction point, composed of hybrid pixel detectors and two outer cylindrical layers of double sided silicon strip detectors. Six forward disks composed of pixel detectors and two external rings of strip detectors. Total readout channels: 10.3 · 10⁶ -pixel part and 2 · 10⁵ -strip part

Thermal simulation of:

One bar made of Al-Alloy (175 W /m·K) with embedded cooling pipe made of AISI 316

ToPix_4:

- ASIC size: 3 mm x 6 mm, clock frequency: 160 MHz
- 130 nm CMOS technology
- Pixel matrix: 640 cells, 2x2x128 and 2x2x32 columns
- Time over Threshold technique implemented, 12 bits dynamic range
- Compatible with the sensor of previous version (ToPix_v3)
- Hamming encoding and TMR pixel logic protection
- Leading and trailing edge registers with DICE -protected latches SEU protected EoC
- Serial data output (SDR and DDR)
- GBT compatible SLVS I/O





- Epitaxial silicon wafer by ITME (Varsaw) ρ_{epi} ~ 1500 Ω·cm Pixels @ FBK (Trento)
- 100μm x 100μm
- Cz thinning + Bump bonding @ IZM (Berlin) Sn-Pb bumps
- Bump bonding yield of the tested assemblies: ~ 99.5 % Thin Cz layer is the ohmic contact for the sensor biasingv









SEU tests of ToPix_4 with ion beams @ LNL-INFN. Study of the configuration registers inside the pixels. **SEU cross section lower of an order** of magnitude with respect ToPix_3 (D type flip-flops circuits with TMR instead of latches circuits with TMR)





ToT @ several discharge current of the feedback Capacitor













Thickness

• 285 μm

Strip sensor shape

Double sided silicon strip

rectangular for the barrel

• 130 μ m / 90° for the barrel

• 70 μ m / 15 ° for the disk

trapezoidal for the disk

Readout: pitch/ stereo angle

detectors







Conclusion

MVD design is in progress with parallel software development to check physics performance The prototyping phase is underway with challenge aspects

